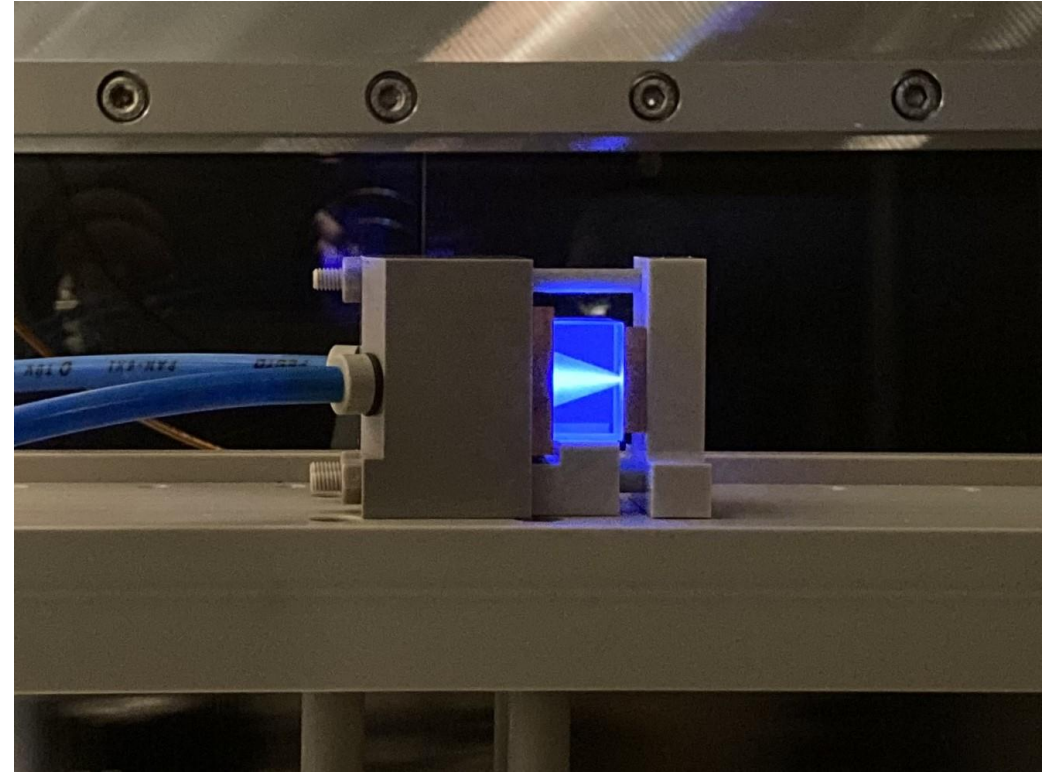


Update on plasma stability measurements of the prototype plasma lens for positron matching



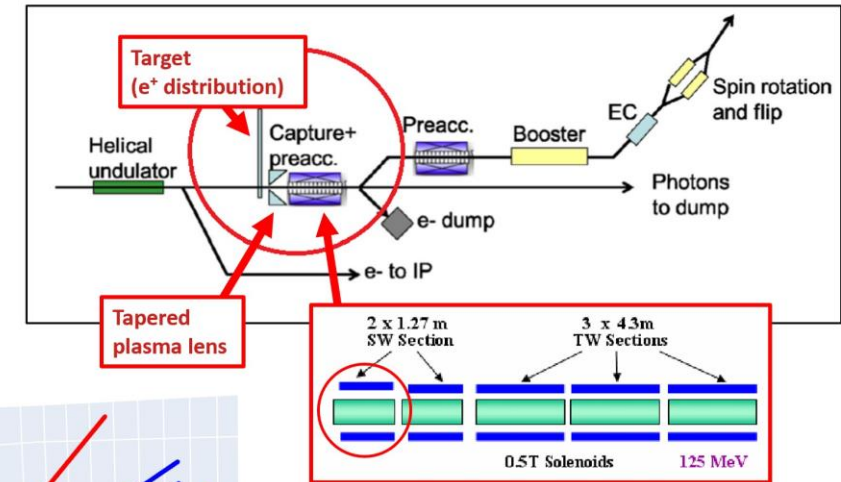
N. Hamann¹, M. Formela¹, G. Loisch², K. Ludwig², J. Osterhoff³, G. Moortgat-Pick^{1,2}

1: Universität Hamburg, 2: DESY Hamburg, 3: Berkeley Lab

niclas.hamann@desy.de

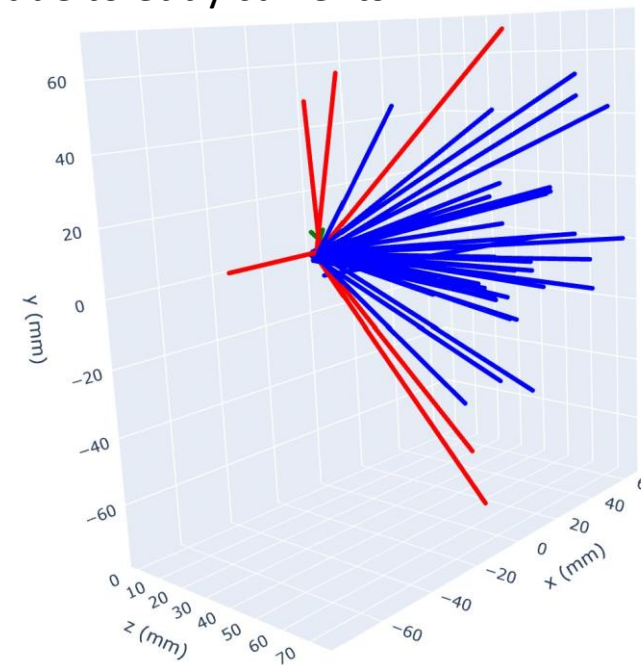
Motivation

- Plasma lens development for undulator-based ILC positron source concept
 - fast rotating Ti wheel with incident high energy photons producing e^+/e^- pairs
- Alternative beam optics, as previous methods do not meet the requirements
 - Low positron yield or heat load on the target due to eddy currents



Beam structure:

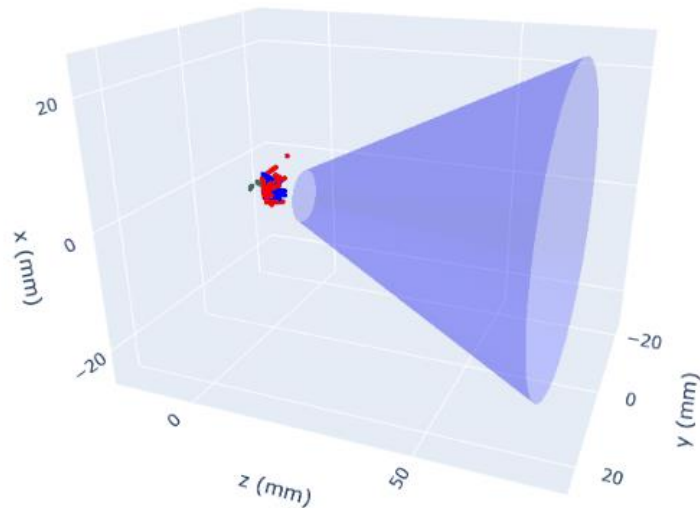
- Pulse repetition rate: 5 Hz
 - per pulse ~ 1300 bunches
- Bunch spacing: 554 ns
 - Repetition rate of plasma lens in MHz
- Average e^+ energy: 6.1 MeV
- Energy spread: 4.8 MeV
- Divergence: 63.28 – 75.24 mrad



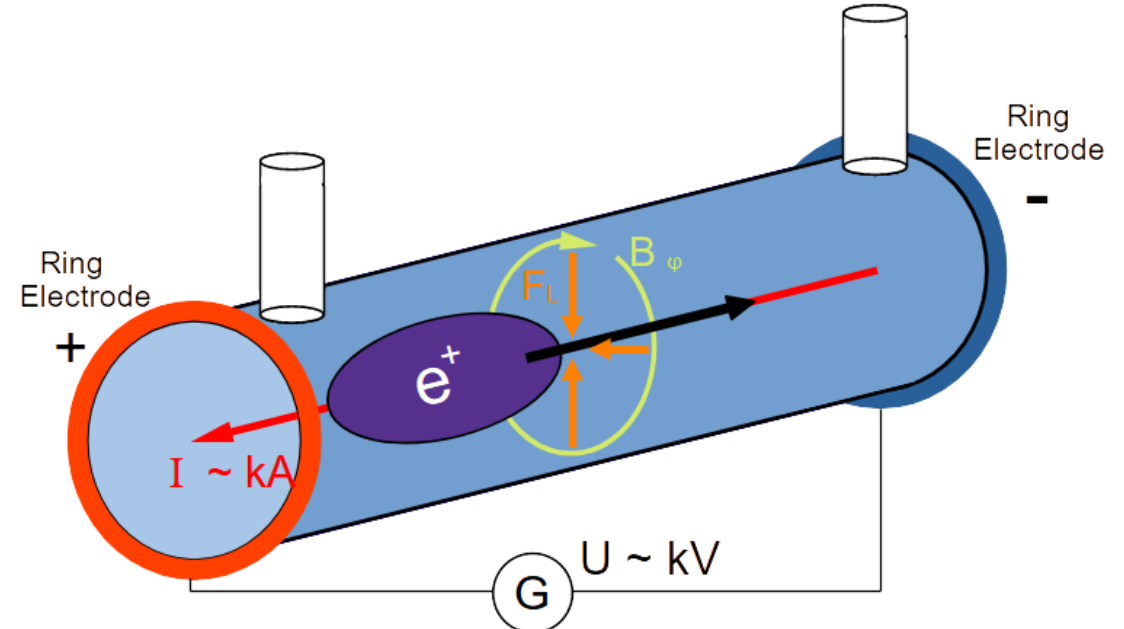
- 1) J.W. Wang, Positron Injector Accelerator and RF System for the ILC, 2007
- 2) F. Dietrich, Status of the undulator-based ILC positron source, 2019

Plasma lens - principle

- Azimuthal magnetic field component
→ No helical pathway of positrons
- So far mostly constant radius focusing channels are used
- Our case: Cone shape to adjust diameter to the envelope of the diverging beam



Particle tracks inside tapered plasma lens



Focusing principle of plasma lens with constant radius
I: Current, U: Voltage, G: HV Generator

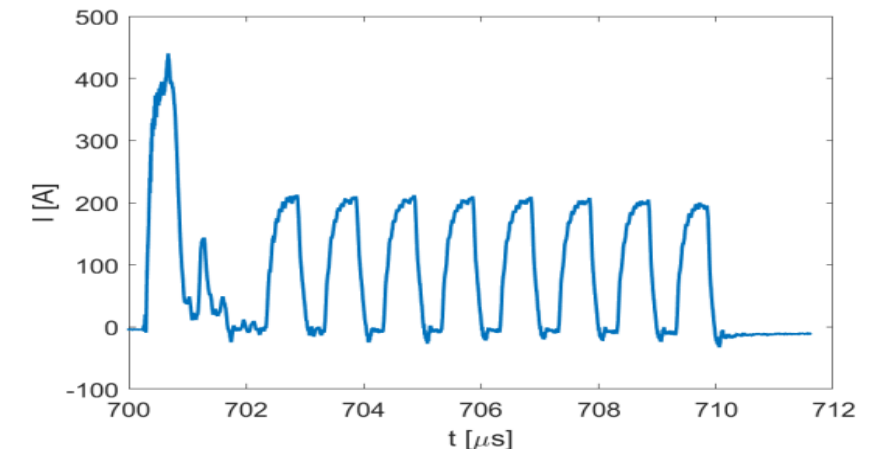
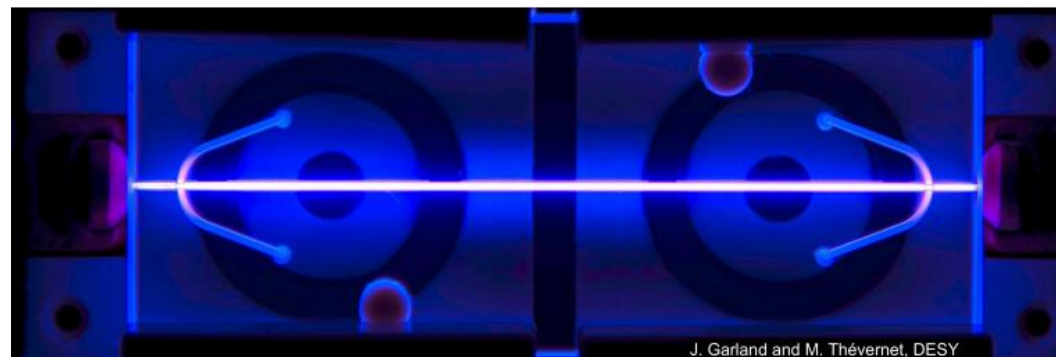
- Direct focusing of positrons onto the beam axis
→ Broader energy acceptance than other positron matching devices

Development of own tracking code

- Ongoing development of own tracking simulation specifically for plasma lenses
- Goal: 1) Automated optimisation of plasma lens parameters for arbitrary particle distributions with respect to different target parameters
2) Simple implementation of different models of magnetic field/current distributions
- Optimization based on Bayesian Optimization
- Already included: simple plasma lens model, constant solenoid and standing wave tube
- Current status:
 - Bayesian Optimization already working for active particle count (with or without long. cut) of nonparallel simulations

ADVANCE laboratory at DESY Hamburg

- Already existing discharge plasma lab
 - Diagnostics and infrastructure available
 - Constantly in development
- Highly flexible vacuum chamber for plasma cells up to 1 m in length
- Multiple HV pulse modulators
- Optical emission spectroscopy and two-color laser interferometry
- On-site plasma source design and production



G. Loisch, Pulsed power electronics to drive plasma sources for future particle accelerators, Poster EAPPC

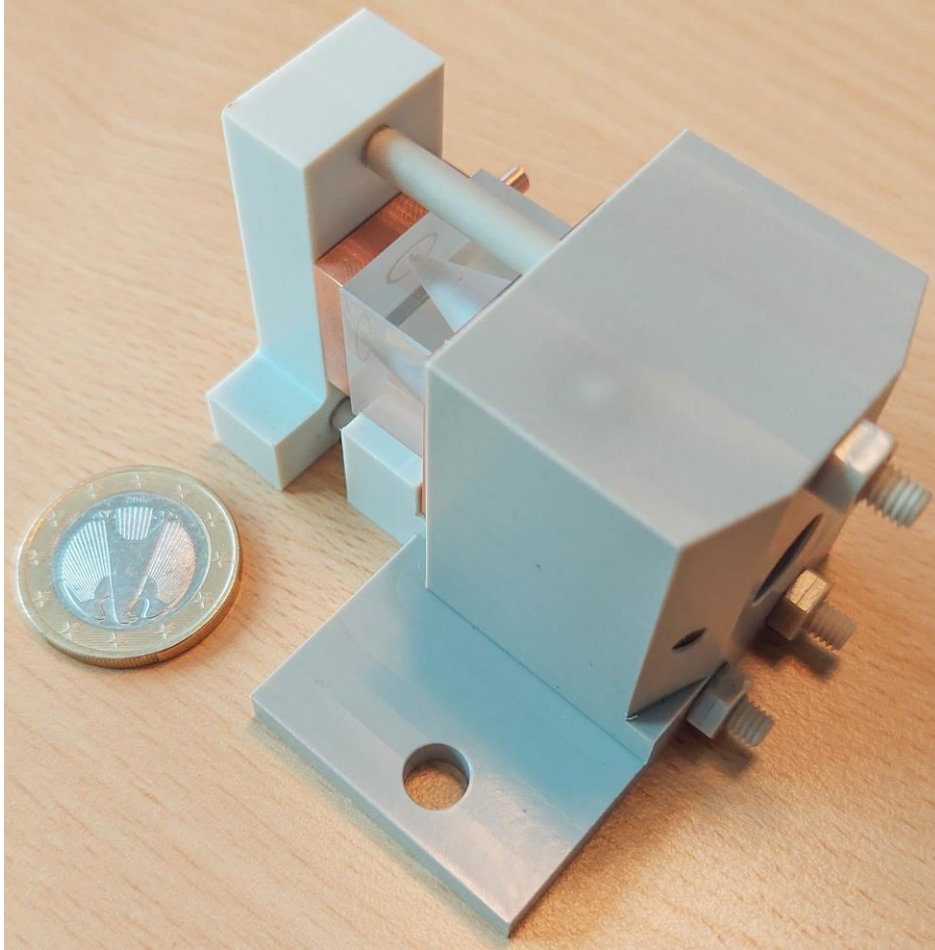
Down-scaling the prototype

- Future setup at ADVANCE Laboratory at DESY Hamburg
- Already existing vacuum chamber und MHz pulse modulator
 - Existing maximum current ~ 350 A
 - Max. leakage rate of $1.7 \text{ Pa} \cdot \text{m}^3/\text{s}$ results in max. mass flow rate of $2.72 \cdot 10^{-5} \text{ kg/s}$ (Argon)
- Same current density in prototype → Scaling dimensions of plasma lens
- Factor for scaling $b = \frac{\sqrt{9000A}}{\sqrt{350A}} \approx 5.07$

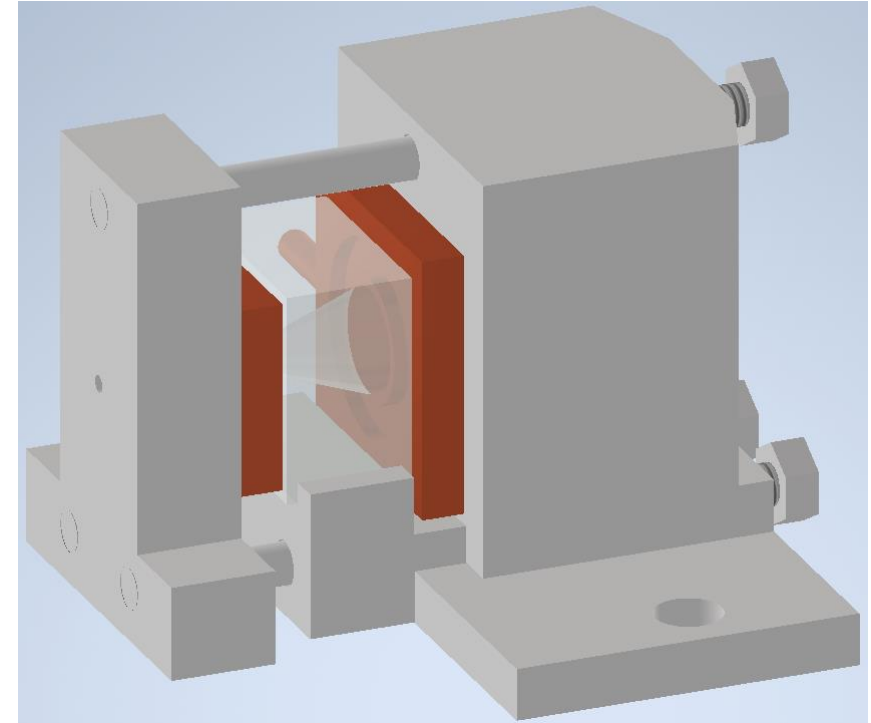
Peak current strength	I_0	350 A
Opening radius	R_0	0.848 mm
Ending radius	R_1	5.029 mm
Tapering parameter	g	0.416 mm^{-1}
Length	L	11.832 mm

Parameters of down-scaled plasma lens

Finished Prototype



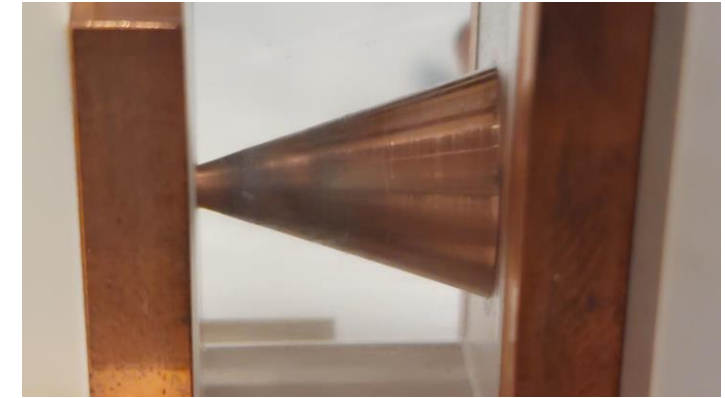
Assembled down-scaled plasma lens prototype



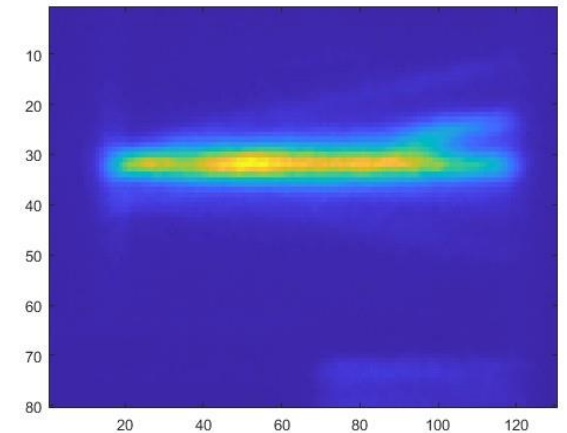
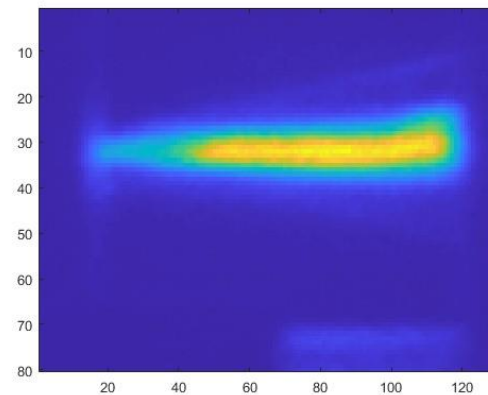
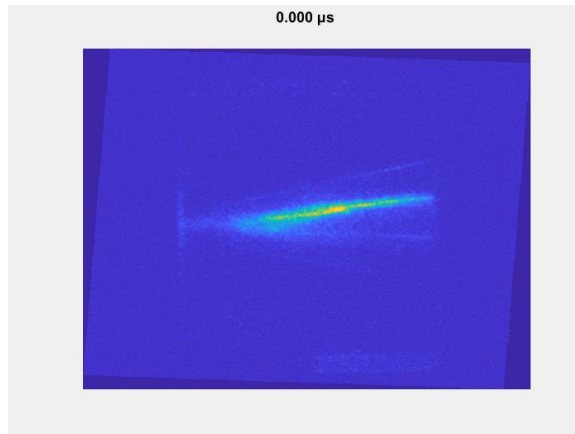
CAD drawing of assembled plasma lens set-up

Observed problems

- Copper coating of the plasma lens
 - Blocking light of plasma for the camera to detect
 - Probably changing plasma/current distribution
- Discharge has unstable behaviour under certain circumstances
 - Splitting into two discharge channels
 - Flickering of discharge channel towards positive y-axis
- Plasma production mainly around beam axis

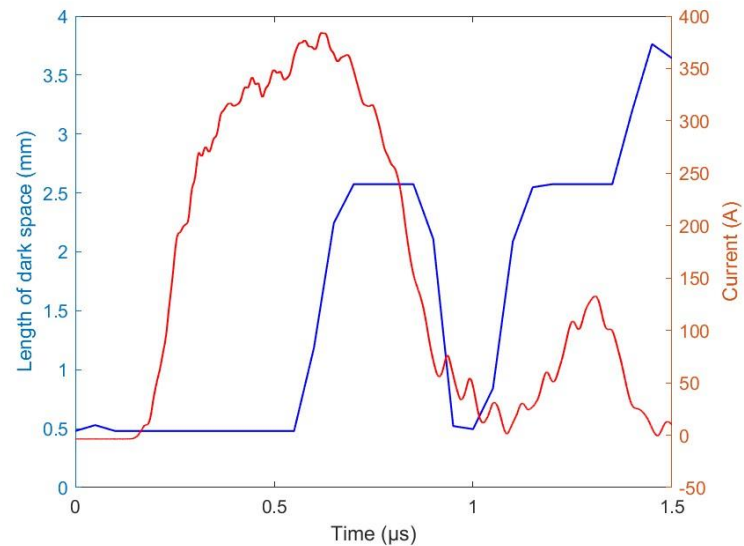


Picture of coated plasma lens after 8 days of testing



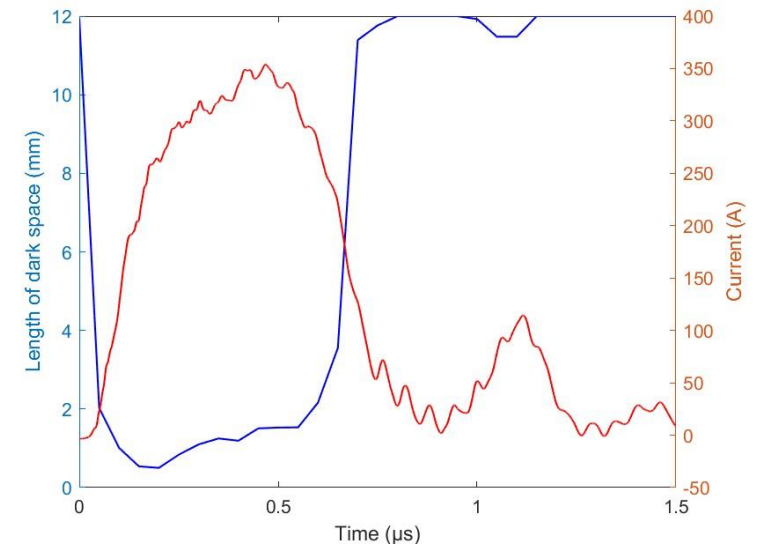
Coated surface comparison

- Measurements on 28.02 and 06.03. Approx.: 22.270 shots in between
- Parameters: Flow rate: 1.5 mbar*I/s, Cable pulser: 20 kV, 0 μ s – 1.5 μ s, Exposure 50 ns, 31 steps with 100 shots each
- Only difference: reversed electrodes
- Threshold for plasma light detection: 120
- First preliminary results, still time needed!



Data taken on 28.02.24

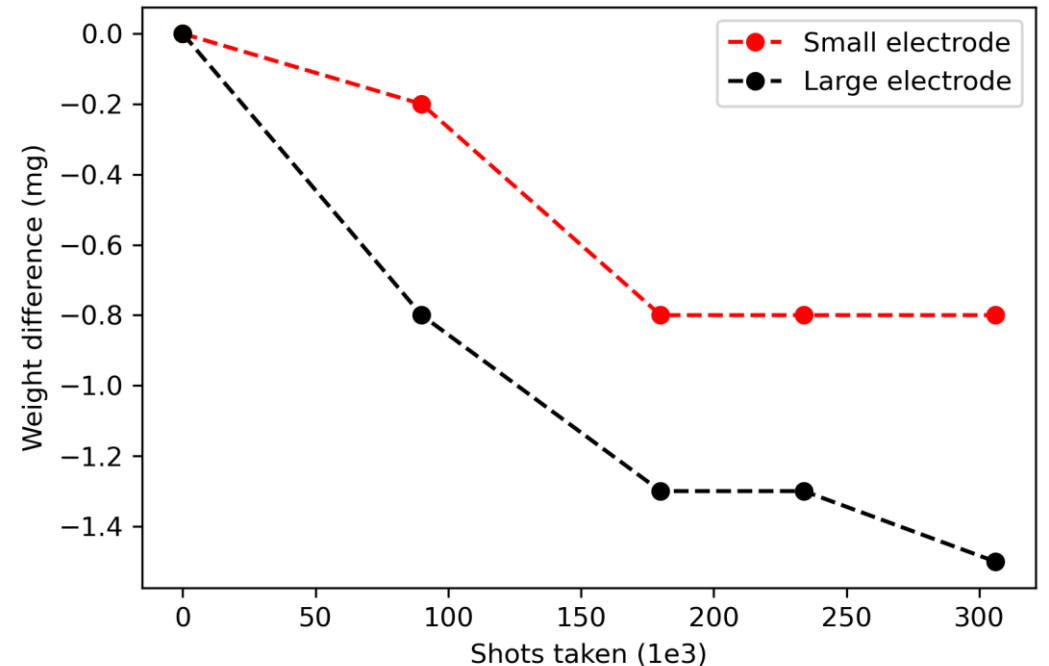
Copper coating shields light from being detected!



Data taken on 06.03.24

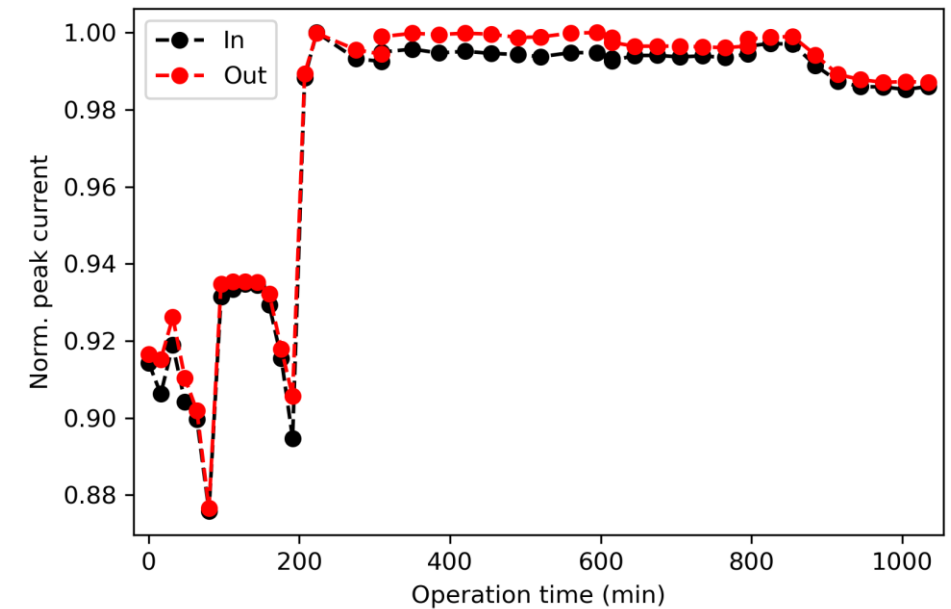
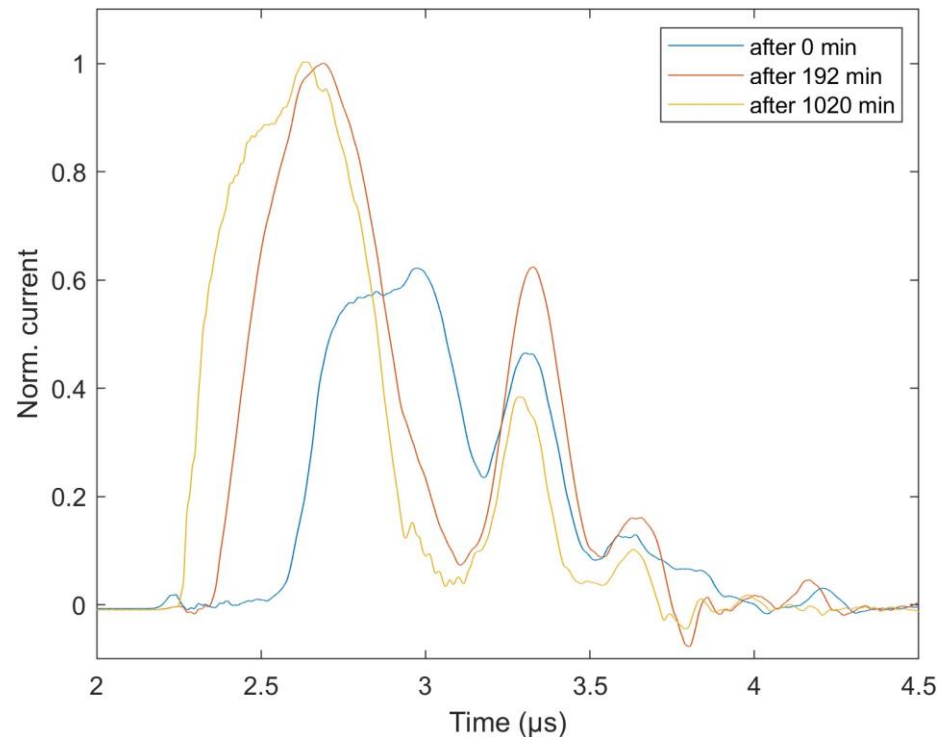
Total loss of copper material

- Longevity test of copper electrodes
- Operation time in total 1035 min (~300k shots)
- Parameters: Flow rate: 0.3 mbar*l/s, Cable pulser: 20 kV
- Weight measured after: 0, 90k, 180k, 234k, 306k shots
- Most significant change inside the first 180k shots
 - Possible conditioning of plasma cell/electrodes
- Electrode erosion is probably pressure dependent
 - More measurements at different pressures
- Other dependencies have to be investigated (peak current, integrated current)



Change of electrical current

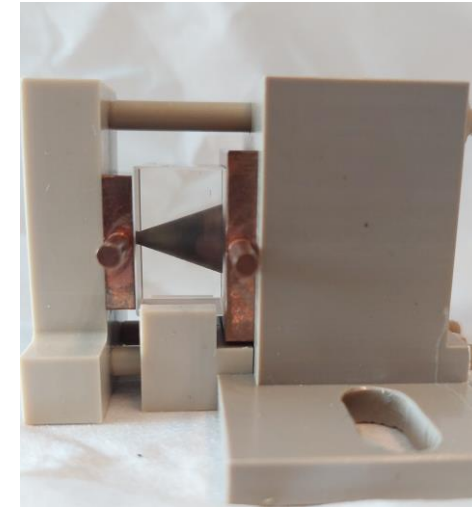
- Recording of ingoing and outgoing current every 15 min to 30 min
- Sudden increase of overall peak current after 200 min (~60k shots)



- Decrease of second peak after ~260 min
 - Reflection of current because of imperfect impedance matching
 - Possible change of resistivity inside plasma lens

Conclusion and outlook

- Plasma lens has high potential (positron yield up to factor 2 better than Quarter Wave Transformer)
- Operation down-scaled prototype for testing due to high requirements
- Ongoing BMBF grant for prototyping of plasma lenses for the ILC e+ source
 - Development of own particle tracking code ✓
- Tapered plasma lenses are largely unexplored
- High temporal resolution imaging at ADVANCE LAB at DESY ✓
 - Comparison of coated surface between 22.000 shots ✓
 - First measurements of copper electrode erosion ✓
 - Additional measurements to investigate dependencies (Pressure, Overall current, Tungsten-copper electrodes)



Thank you for your attention!

References

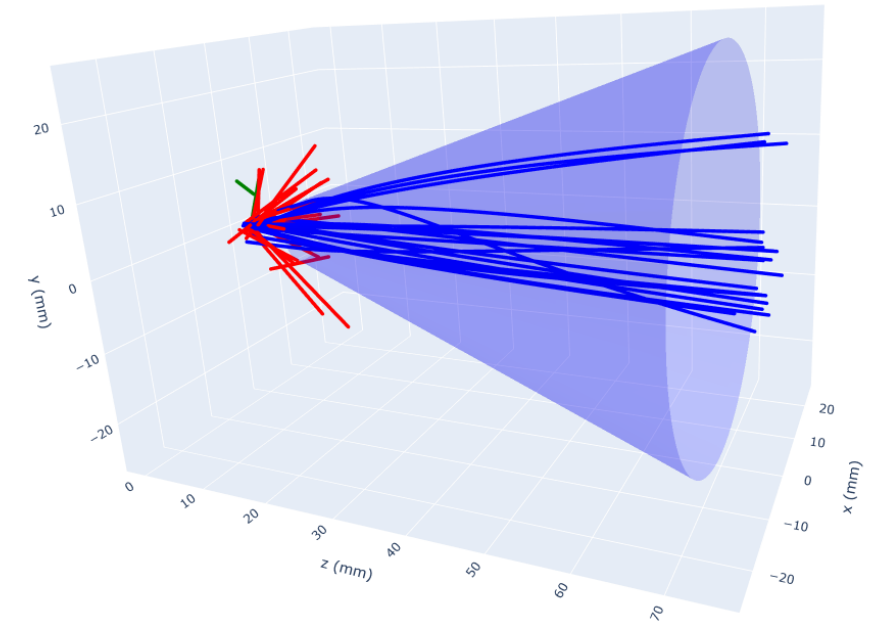
- M. Barish, B. Buesser, K. Adolphsen, C. Barone: Technical Design Report | Volume 3.I: Accelerator RD, 2013
- K. Flöttmann: ASTRA: A space charge tracking algorithm, 2017, <https://www.desy.de/~mpyflo/>
- J. W. Wang: Positron Injector Accelerator and RF System for the ILC, APAC 2007
- F. Dietrich: Status of the undulator-based ILC positron source, 2019
- M. Fukuda: private communication, 2019
- M. Fukuda, Development of Start-to-End Simulation for ILC positron sources, <https://indico.cern.ch/event/727621/contributions/3114267/> POSIPOL 2018
- G. Loisch: Jitter mitigation in low density discharge plasma cells for Wakefield accelerators, 2019
- G. Loisch: Demonstrating High Transformer Ratio Beam-Driven Plasma Wakefield Acceleration, PHD thesis, 2019
- G. Moortgat-Pick, A. Ushakov: The ILC Positron Source <https://indico.cern.ch/event/356420/contributions/1764521/attachments/1132036/1618360/source-eps.pdf>
- M. Formela: Particle-Tracking-Based Optimizations of Plasma Lens Parameters for Optical Matching at the ILC Positron Source, Master thesis 2022
- N. Hamann: Design of a plasma lens test setup for optical matching at the ILC positron source, Master Thesis, 2022
- N. Hamann: Plasma Lens Prototype Progress: Plasma Diagnostics And Particle Tracking For ILC e+ Source, LCWS23, 2023

Beam parameters

- Beam current for 43k positrons: 0.08 mA
- Beam charge for 43k positrons: $6.9 \cdot 10^{-6}$ nC
- Beam current for 1 pulse: 5.8 mA
- Beam charge for 1 pulse: 4204 nC

Particle tracking simulations with ASTRA

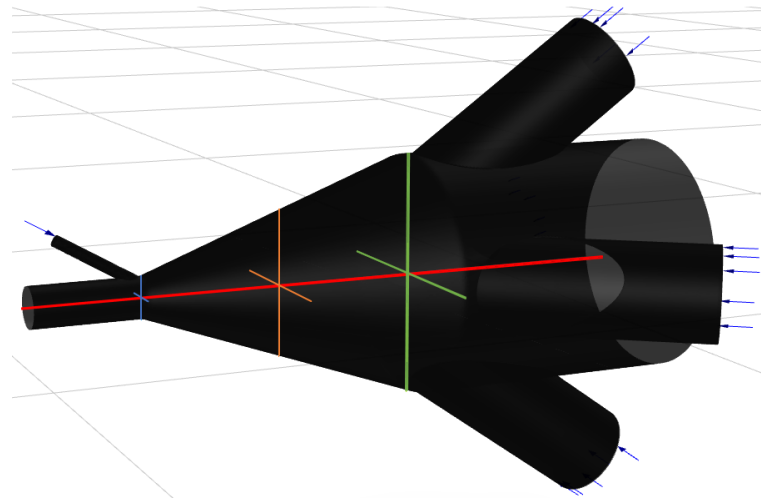
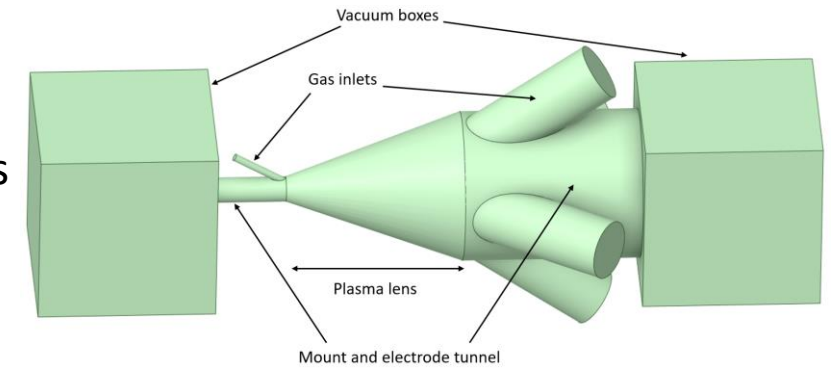
- Common positron distribution for ILC e+ source
- Simulations based on ASTRA code (K. Flöttmann)
- Simplifications: no space charge, homogeneous current density, no edge fields
- Energy acceptances
 - Longitudinal cut: ± 7 mm
 - taken from M. Fukuda (ILC Positron Group)



Positron Energy	5 GeV
Dynamic Aperture	<0.07 mrad
Energy Acceptance	0.75 %
Longitudinal Acceptances	3.4 x 37.5 cm-MeV
Longitudinal Emittance	0.75 x 33 % x mm

Gas flow simulations with ANSYS Fluent

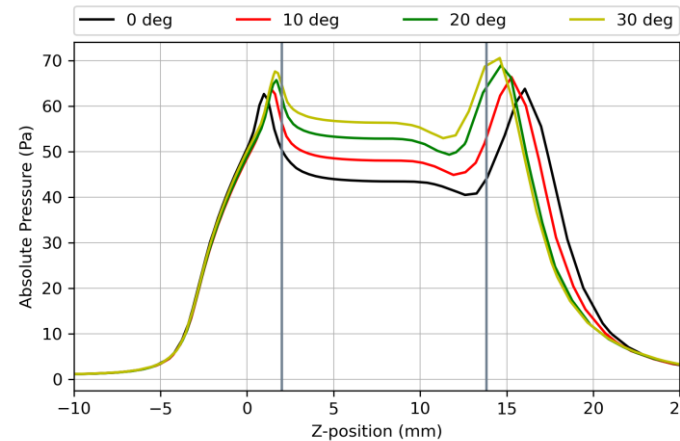
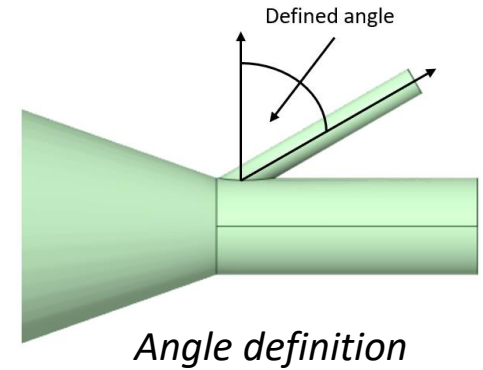
- Influence of gas inlet geometry on gas distribution within plasma lens
- Goal: Pressure distribution as uniform as possible
- Simulations consists of plasma lens, gas inlets, extensions for electrodes and insulators and vacuum boxes for gas flow outside of plasma lens
- Target pressure: 50 Pa, mass flow rate: $2.4 \cdot 10^{-5}$ kg/s (Argon)



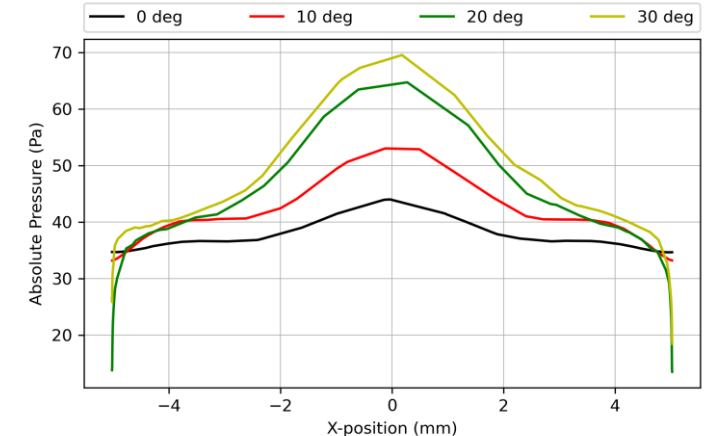
- Pressure profile along drawn lines
- X- and Y-axis show similar results
→ Only X-axis is shown

Angle of gas inlets

- Angle from 0 degrees to 30 degrees in 10 degree steps
- Four inlets with 2 mm diameter at the exit
- Two inlets with 0.48 mm diameter at the entry
- Higher pressure in the plasma lens due to larger angles
→ Gas is shot directly into the plasma lens
- Gas accumulation in the extensions in front of and behind the plasma lens



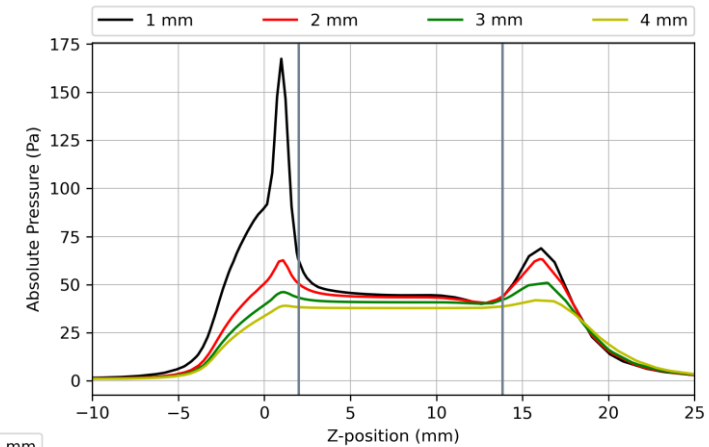
*Pressure profile along the Z-axis
Grey lines indicate the plasma lens*



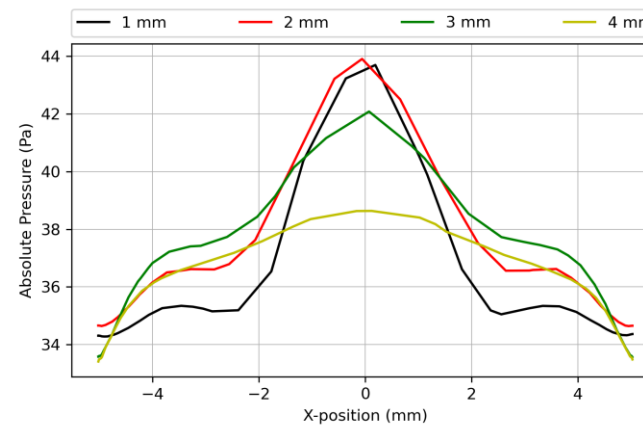
*Pressure profile along the X-axis at
the output*

Gas inlet diameter

- Diameter of inlets at the exit from 1 mm to 4 mm in 1 mm steps
- No angles for all inlets (0 degrees)
- Four inlets at the exit and two 0.48 mm at the entry
- Larger diameters lead to lower pressure in the plasma lens
- Larger diameters distribute the gas accumulations more evenly
- Gas pressure at the entry can be modulated by inlets at the exit



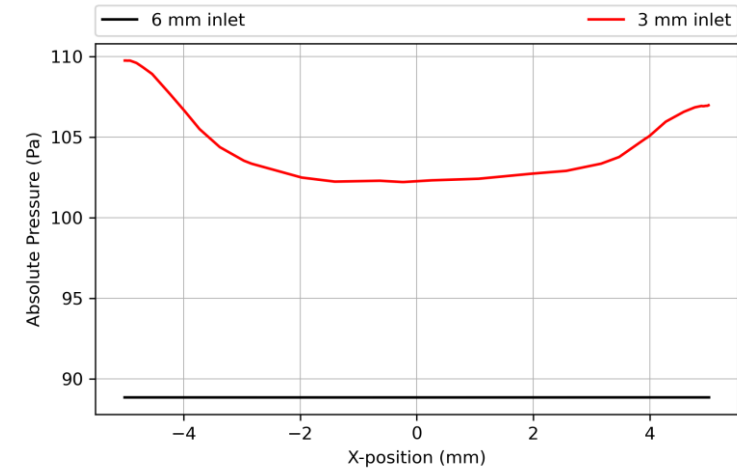
Pressure profile along the Z-axis



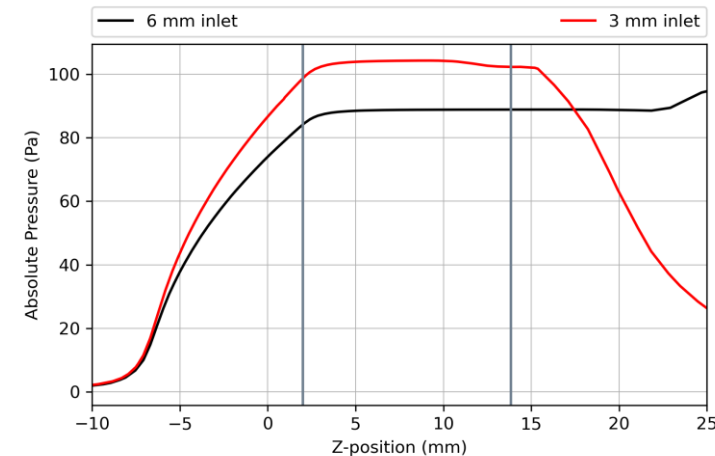
Pressure profile along the X-axis at the exit

Design simplification for prototype setup

- Goal: Adapt structure to laboratory and manufacturing conditions
- No inlets at the entrance (too small)
- Fewer inlets
- Target pressure adjusted to 100 Pa for lab environment
- Mass flow rate $2 \cdot 10^{-5}$ kg/s for Argon
- No inlets at the entry
- 2 inlets at the exit
- Angle: 70 degrees
- Two versions: 6 mm and 3 mm diameter, same mass flow rate
- 3 mm achieve higher overall pressure
- 6 mm more even distribution along the Z-axis



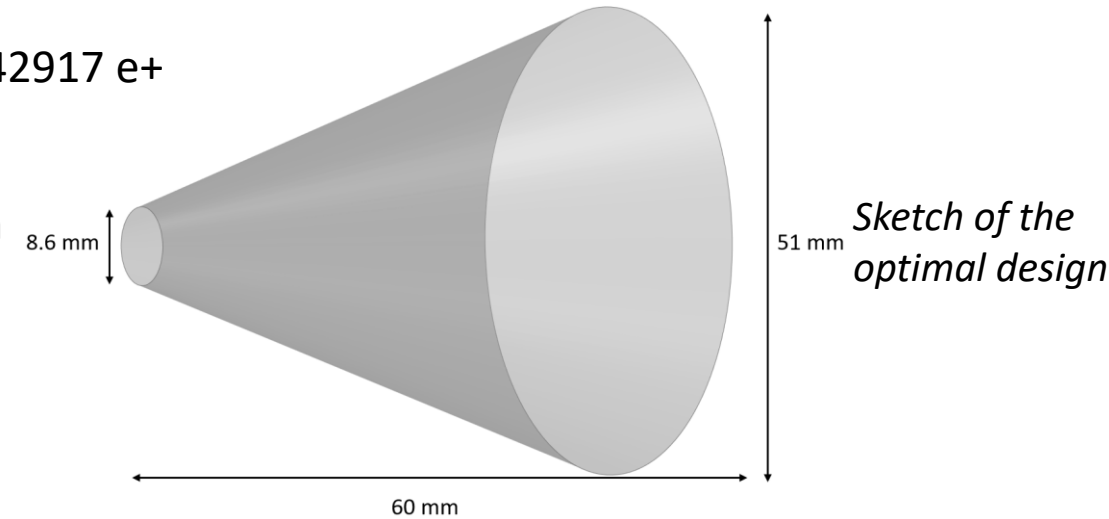
Pressure profile along the X-axis at the exit



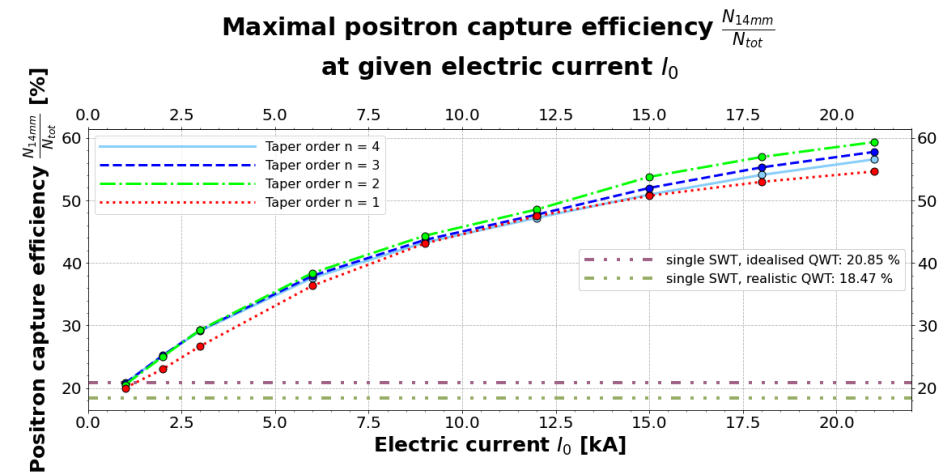
Pressure profile along the Z-axis

Particle tracking simulation results

- Result: After long. cut (14 mm) 44.35 % capture efficiency of 42917 e+
- Highest currents produce highest capture efficiency
 → current limited to ~9kA to reduce electrode erosion



Parameter name	Symbol	Optimal Value
Plasma Lens Length	z_{max}	60 mm
Opening Radius	R_0	4.3 mm
Tapering Order	n	2
Tapering Strength	g	0.082 mm^{-1}
PL-SWT distance	d	10 mm
SWT Phase	φ_0	225 deg
Current strength	I_0	9 kA

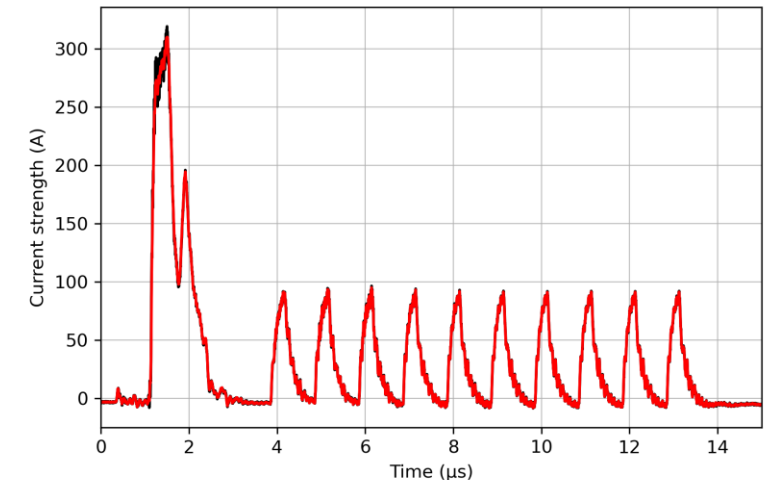
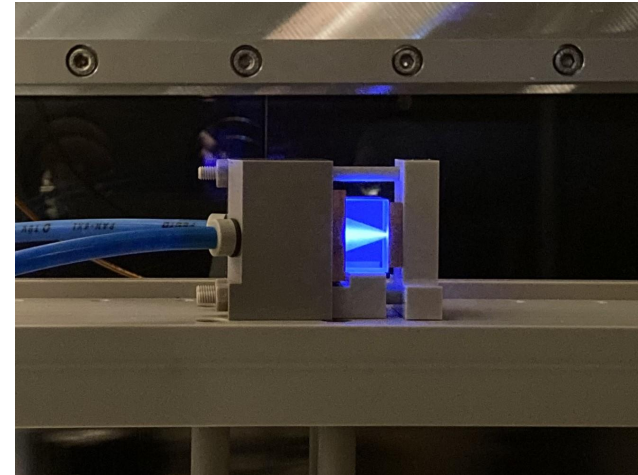


Update on the latest tests

- Used gas: Argon
- Flow rates: 0.2 mbar*l/s – 1.5 mbar*l/s
- Cable pulser: 20 kV
- Glow discharge: < 5 kV
- ICCD exposure time: 50 ns

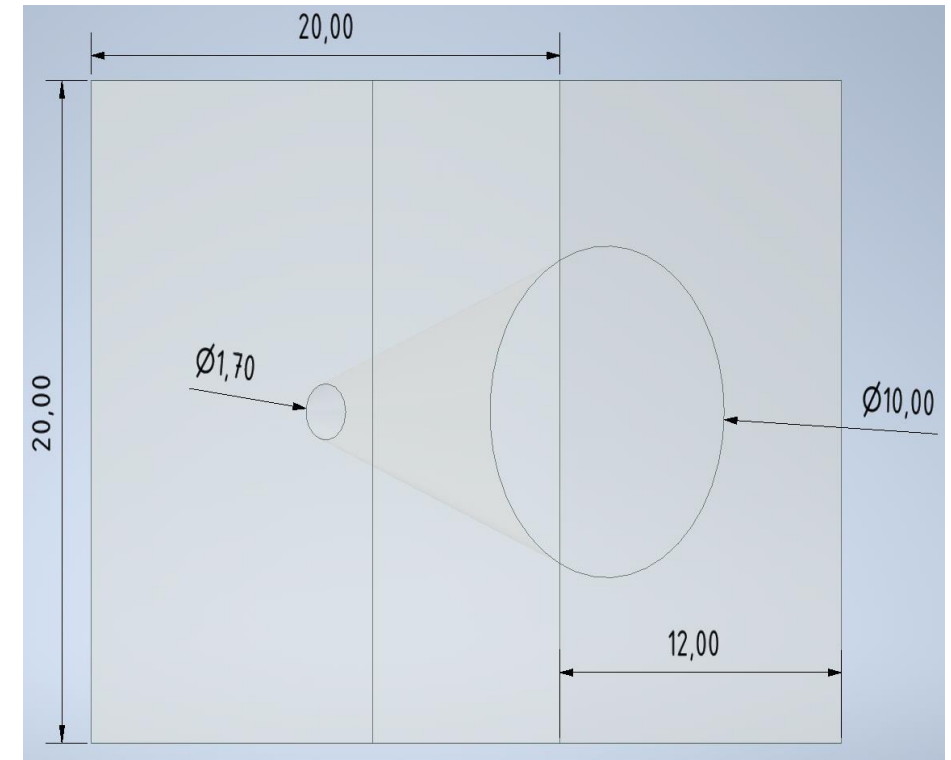
- Measurements taken:
 - Plasma development from 0 μ s – 1.5 μ s taken at different flow rates
 - Comparison of plasma development with glow discharge
 - Long time plasma evolution up to 4 μ s
 - Plasma stability with reversed electrodes
 - Breakdown voltage for different flow rates

Detailed analysis still ongoing!



Technical design concept – gas cell

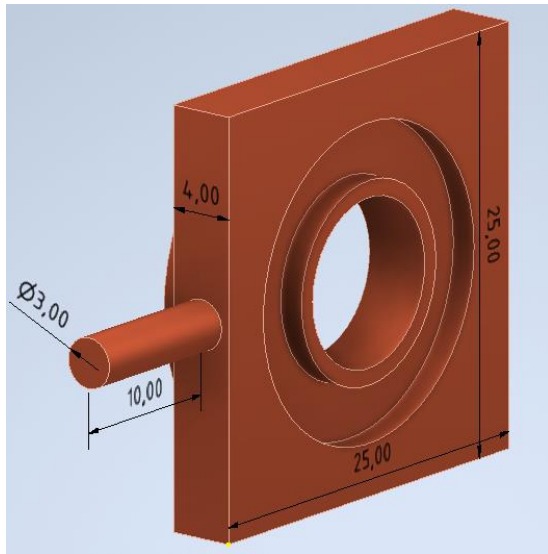
- Mounts for fixating positions of plasma lens and electrodes made out of PEEK
- Electrodes made out of copper
- Plasma lens made of 20 mm x 20 mm x 12 mm sapphire block
- Principle: lens is pressed in between PEEK mounts with threaded rods and sealed with O-rings
- All specifications of technical designs noted in mm



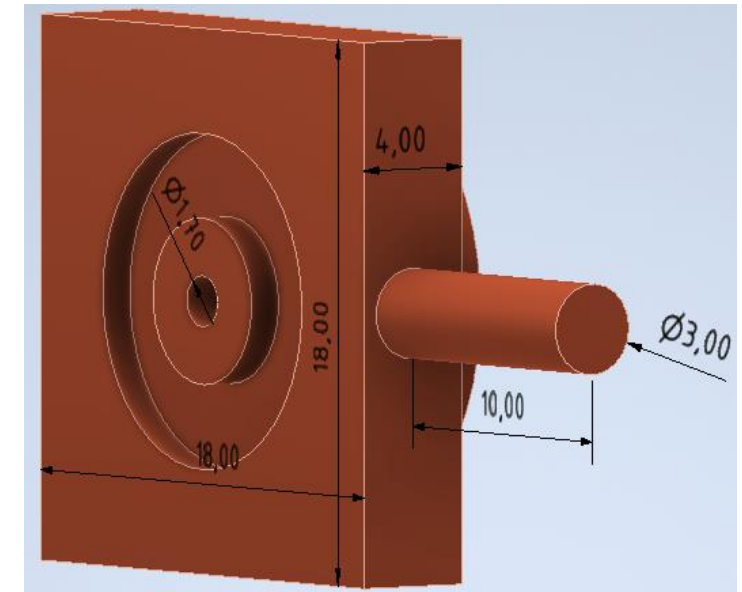
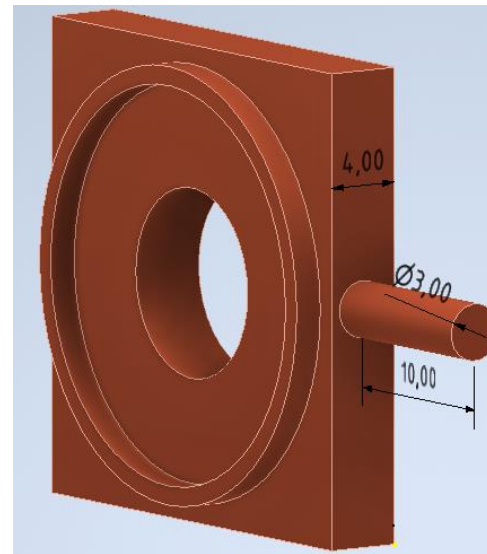
Plasma lens

Technical design concept - electrodes

- Electrodes with central hole
→ Diameter 1.7 mm and 10 mm
- Groove for O-ring with 1.5 mm and 2 mm cord thickness
- Ring extensions placed into red groove of PEEK mounts
- Pins for connecting the electrodes



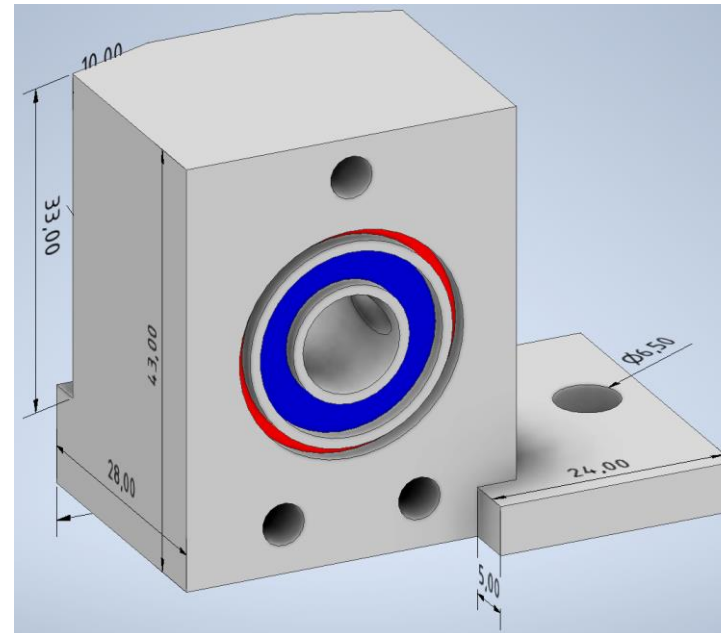
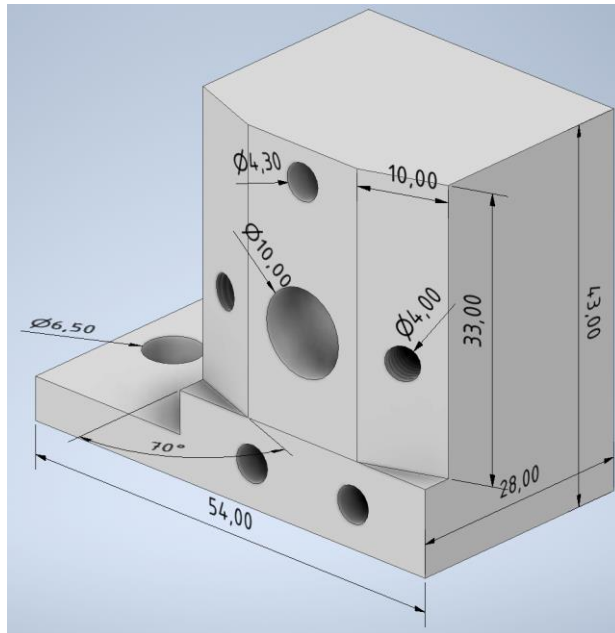
Electrode at the exit



Electrode at the entry

Technical design concept – gas supply

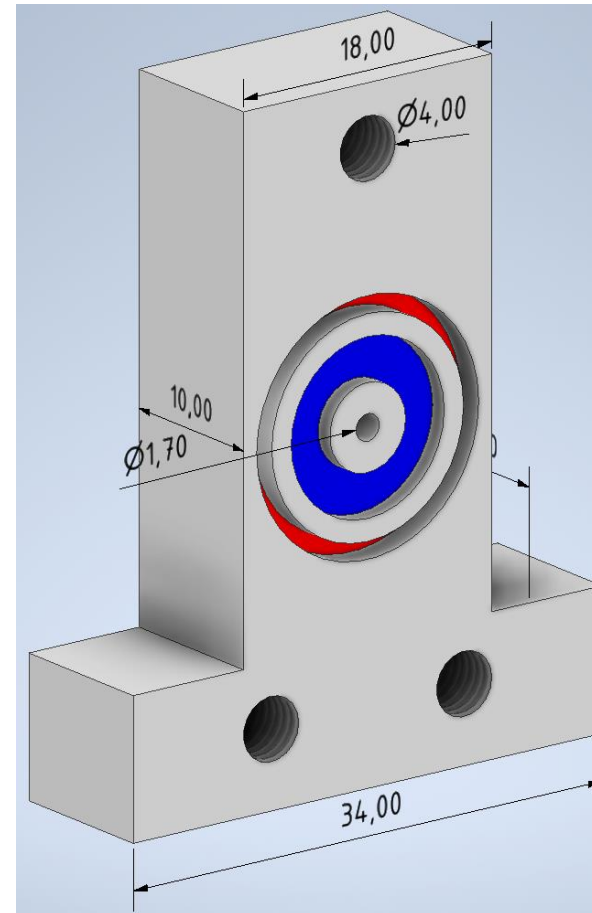
- Mount at entry, exit and bottom of plasma lens
- 3 mm gas inlets on bevelled edges with 70 degrees
- Blue groove for O-ring with thickness of 2 mm
- Red groove for positioning the electrode



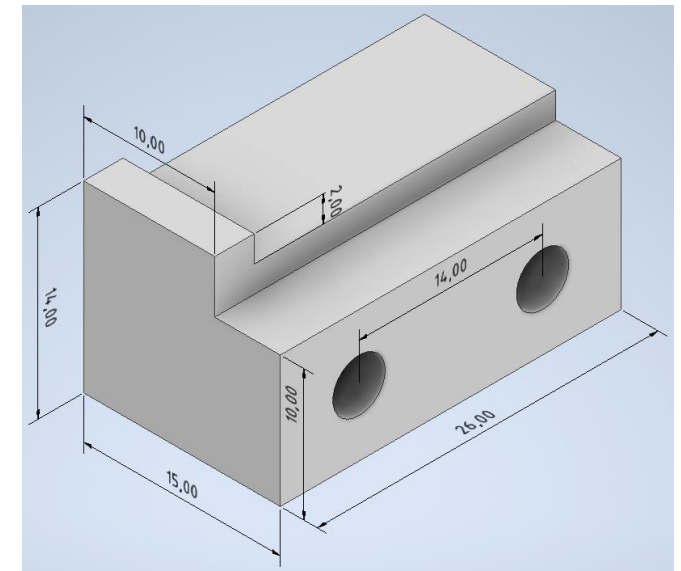
Mount at the exit with gas inlets

Technical design concept - support

- Mount with the same concept as at the exit
→ Exception: no gas inlets
- Edge on bottom mount to fix position of plasma lens
- Bottom mount should not touch electrode
→ Would over-define position
- Blue groove for O-ring with thickness of 1.5 mm
- Red groove for inlet of electrode



Mount at the entry



Mount below the plasma lens